



Docket No. 51380

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT: Takashi et al.  
SERIAL NO. 10/078,766 GROUP: 1742  
FILED: February 19, 2002 EXAMINER: W. Leader  
FOR: PROCESS FOR ELECTROPLATING SILICON WAFERS

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Applicants are in receipt of the Office Action dated September 17, 2003 of the above-identified application. Please amend the application as follows.

A listing of pending claims begins on page 2 of this paper.

Remarks begin on page 4 of this paper.